# The study of uniformity in direct readout SiPM tiles 

ITEP, MEPhI, MIPT

## International Linear Collider

To study the Higgs Boson properties
To be build in Japan in 2027


## Fiber readout

30x30x5 mm3 tile


30x30x3 mm3 tile


RMS/Mean with 1mm precision 7\%
$10 \%$
RMS/Mean with 2mm precision
6\%
$7 \%$

## Direct readout

- ~3 000000 tiles are needed
- Wavelength shifting fiber is prepared and installed manually. This is expensive and time consuming
- An attempt of direct readout is made


## Hadron Calorimeter Configuration

- Introduced by Northern Illinois University
- With the direct readout we can combine electronic planes and scintillator planes in the latest stage


Picture from NIU work

## Uniformity

- The key concern when using direct readout is light collection uniformity
- The central value is 3 times bigger, than others. RMS/Mean is $\sim 80 \%$ $\uparrow$ - nonuniformity



## The setup

2 parts

- Programmable milling machine with the software modified to be able to mill a generic shape hole in a tile
- The automated uniformity measurement setup, consisting from 3 axis cartesian manipulator with a radioactive source and software for control and results processing.


## Milling



## The setup

- Manipulator with mounted 90Sr beta-source and trigger tile. Collimator size is 1 mm .


## The setup

- SiPM in the upper mirror



## Measurements

- Only particles passed through the studied tile are used (with the signal in trigger tile)
- The spectrum of signals from their passes is considered (number of particles with vs ADC from SiPM)
- Fit it with gaussian



## Tile shape

- Parallelepiped with the hole in the center of the flat face in the form of paraboloid. It has two parameters the depth and radius of the hole on the surface.


## 2d scans

0 on z-axis on the plots is placed in the minimum of the distribution. The scan precision is 3 mm .


Depth 1.7 mm
Radius 8mm
Mean 246
RMS/Mean 10\%


Depth 1.9mm
Radius 8mm
Mean 262
RMS/Mean 10\%

## 2d scans



Depth 1.8mm
Radius 8mm
Mean 272
RMS/Mean 8\%

## Uniformity characterization



Distribution of MP values from MIP over tile

## Optical crosstalk between tiles


3.8\%

2.4\%

Distribution of MP values from MIP over tile

## Another investigations

- Mating and polishing of the surface in front of the SiPM have no effect
- Some light focusing exists - signal is not proportional to the SiPM surface area


## Conclusions

- It is possible to achieve $\sim 10 \% \mathrm{RMS} /$ Mean in direct readout with 1.5 mm scan precision
- The configuration with the separate electronics assembly and SMD SiPM's is enabled
- The selected shape can be easily reproduced with injection molding

Thank you for your attention!

